

RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | In re Application of: |) | |
|----------------|---|-------------|---|
| | Kazunori IWAMOTO et al. | :) : | Examiner: H. Nguyen Group Art Unit: 2851 |
| | Application No.: 09/866,600 | , | 0.0mp o = 0.0 t |
| | T. P. | : | Confirmation No.: 4961 |
| | Filed: May 30, 2001 |) | |
| | For: STAGE APPARATUS WHICH SUPPORTS | ; | October 8, 2003 |
| | INTERFEROMETER, STAGE POSITION | : | |
| , , | MEASUREMENT METHOD, PROJECTION |) | |
| 1 Call | EXPOSURE APPARATUS, PROJECTION | : | |
| | EXPOSURE APPARATUS MAINTENANCE |) | |
| W. O. J. J. C. | METHOD, SEMICONDUCTOR DEVICE | : | |
| All 1 | MANUFACTURING METHOD, AND |) | |
| in the second | SEMICONDUCTOR MANUFACTURING FACTORY | : | |
| | Mail Stop AF | | |
| HW | Commissioner for Patents | | |
| | P.O. Box 1450 | | |

AMENDMENT AFTER FINAL REJECTION

Sir:

In response to the Official Action dated July 8, 2003, please amend the above-identified application as follows:

10/09/2003 SSITHIB1 00000041 09866600 01 FC:1201 86.00 0P

Alexandria, VA 22313-1450